

1/1 IDS 7/21/03

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-2357	priority SERIAL NO. 10/364,054	10/624716	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Luan C. Tran			
				priority FILING DATE February 10, 2003	priority GROUP 2812		

U.S. PATENT DOCUMENTS								
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate		
JH JH JH JH JH JH JH JH JH JH	AA	6,438,666 B2	10-2002	Wasshuber			/	
	AB	6,444,548 B2	09-2002	Divakaruni et al.				
	AC	3,886,003	05-1975	Takagi et al.				
	AD	4,366,338	12-1982	Turner et al.				
	AE	6,008,115	12-1999	Jung				
	AF	6,506,647 B2	01-2003	Kuroda et al.				
	AG	US2001/0036713A1	11-01-2001	Rodder et al.				July 5, 2001
	AH	US2002/0034865A1	03-21-2002	Umimoto et al.				Nov. 30, 2001
	AI	09/876,722		Scott				June 6, 2001
	AJ	10/133,193		McQueen et al.				April 26, 2002
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FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Subclass	Translation		
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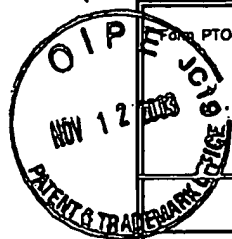
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)		
JH	AQ	Young et al., "A 0.13 $\mu$ m CMOS Technology with 193 nm Lithography and Cu/Low-k for High Performance Applications", IEDM, pgs. 563-566, April 2000.
JH	AR	Yeh et al., "Optimum Halo Structure for Sub-0.1 $\mu$ m CMOSFETs", IEEE Transactions on Electronic Devices, Vol. 48, No. 10, October 2001, pgs. 2357-2362.
JH	AS	Bouillon et al., "Re-examination of Indium implantation for a low power 0.1 $\mu$ m technology", IDEM, pgs. 897-900, 1995 (year is sufficient so that date is not in issue).

EXAMINER <i>James M. Kennedy</i>	DATE CONSIDERED <i>Feb 15, 2005</i>
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1/3 IDS 11/12/03



Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-2357		SERIAL NO. 10/624,716		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Luan C. Tran				
				FILING DATE July 21, 2003		GROUP 2812		
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
JH	AA	6,144,079 A	11-2000	Shirahata et al.				
JH	AB	6,033,952	03-2000	Yasumura, et al.				
JH	AC	6,124,168	09-2000	Ong				
JH	AD	5,688,705	11-1997	Bergemont				
JH	AE	5,866,448	02-1999	Pradceep et al.				
JH	AF	5,858,847	01-1999	Zhou et al.				
JH	AG	6,380,598	04-2002	Chan				
JH	AH	6,060,364	05-2000	Maszara et al.				
JH	AI	6,194,276 B1	02-2001	Chan et al.				
JH	AJ	6,359,319 B1	03-2002	Noda				
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JH	AL	4,937,756	06-1990	Hsu et al.				
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
JH	AM	EP 0718881	06/96	EPO, Chan				
	AN							
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	AP							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
JH	AR		Watanabe, H. et al., <i>Novel 0.44μm<sup>2</sup> Ti-Salicide STI Cell Technology for High-Density NOR Flash Memories and High Performance Embedded Application</i> , IEEE 1998, pp. 36.2.1 - 36.2.4.					
JH	AS		Wolf, S., <i>"Silicon Processing for the VLSI Era"</i> , Vol. 2, pp. 632-635.					
JH	AT		MITSUBISHI ELECTRIC WEBSITE: Reprinted from website <a href="http://www.mitsubishielectric.com/r_and_d/tech_showcase/ts8.php">http://www.mitsubishielectric.com/r_and_d/tech_showcase/ts8.php</a> on 3/29/2001: "8. Production Line Application of a Fine Hole Pattern-Formation Technology for Semiconductors", on 3/29/2001, 4 pgs					
EXAMINER		JENNIFER M. KENNEDY						
		DATE CONSIDERED Feb. 15, 2005						
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U.S. DEPARTMENT OF COMMERCE  
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(Use several sheets if necessary)APPLICANT  
Luan C. TranFILING DATE  
July 21, 2003GROUP  
2812

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Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
QU	AA	5,930,614	07-1999	Eimori et al.		
QU	AB	5,635,744	06-1997	Hidaka et al.		
QU	AC	6,204,536	03-2001	Maeda et al.		
QU	AD	6,515,899 B1	02-2003	Tu et al.		
QU	AE	4,570,331	02-1986	Eaton, Jr. et al.		
QU	AF	6,429,079 B1	08-2002	Maeda et al.		
QU	AG	6,607,979 B1	08-2003	Kamiyama		
QU	AH	4,686,000	08-1987	Heath		
QU	AI	5,814,875	09-1998	Kumazaki		
QU	AJ	5,654,573	08-1997	Oashi et al.		
QU	AK	6,479,330 B2	11-2002	Iwamatsu et al.		
QU	AL	6,586,803	07-2003	Hidaka et al.		

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## OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

QU	AR	CAHNERS SEMICONDUCTOR INTERNATIONAL WEBSITE: Reprinted from <a href="http://www.semiconductor.net/semiconductor/issues/1999/sep99/docs/feature1.asp">http://www.semiconductor.net/semiconductor/issues/1999/sep99/docs/feature1.asp</a> on 3/29/2001: "Resists Join the Sub- $\lambda$ Revolution", 9 pgs.
QU	AS	CAHNERS SEMICONDUCTOR INTERNATIONAL WEBSITE: Reprinted from <a href="http://www.semiconductor.net/semiconductor/issues/1999/aug99/docs/lithography.asp">http://www.semiconductor.net/semiconductor/issues/1999/aug99/docs/lithography.asp</a> on 3/29/2001: "Paths to Smaller Features", 1 pg.
OK	AT	Wolf, S., "Silicon Processing for the VLSI Era, Vol. 1: Process Technology," Lattice Press 1986, pp. 434-437.

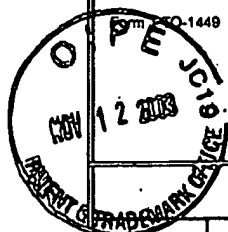
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DATE CONSIDERED

Quinn M. Kennedy Feb 15, 2005

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3/3 IDS 11/12/03



U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2357		SERIAL NO. 10/624.716	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Luan C. Tran	
FILING DATE July 21, 2003				GROUP 2812	

U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
AA	6,552,401 B1	04-2003	Dennison				
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AC	US2002/0182829A1	12-2002	Chen				
AD	US2002/0164846A1	11-2002	Lin et al.				Apr. 19, 2002
AE	US2003/0071310A1	04-2003	Salling et al.				Oct. 11, 2001
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		Document Number	Date	Country	Class	Subclass	Translation
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AR		"Session 18: Integrated Circuits and Manufacturing - DRAM and Embedded DRAM Technology," 2001 IEDM Technical Program, 2001 IEEE International Electron Devices Meeting, Dec. 4, 2001, reprinted 11/15/01 from <a href="http://www.his.com/~iedm/techprogram/sessions/s18.html">http://www.his.com/~iedm/techprogram/sessions/s18.html</a> , pp. 1-2.	
AS			
AT			

EXAMINER	DATE CONSIDERED
Jennifer M. Kennedy	Feb 15 2005

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Form PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO.  
M122-2357

SERIAL NO.  
10624716

LIST OF ART CITED BY APPLICANT  
(Use several sheets if necessary)

APPLICANT  
Leah C. Tran

FILING DATE  
July 21, 2003

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2811

U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
QU	AA	6,521,487 B1	02-2003	Chen et al.			
QU	AB	6,492,694 B2	12-2002	Nohle et al.			
QU	AC	6,468,865 B1	10-2002	Yang et al.			
QU	AD	6,451,704 B1	09-2002	Pradeep et al.			
QU	AE	6,436,747 B1	08-2002	Segawa et al.			
QU	AF	6,362,004 B1	03-2002	Sanford et al.			
QU	AG	6,277,720 B1	08-2001	Umhi et al.			
QU	AH	5,923,975	05-1999	Rohadi			
QU	AI	5,866,934	02-1999	Kudush et al.			
QU	AJ	5,180,468 B1	01-2001	Yu et al.			
QU	AK	6,207,310 B1	03-2001	Abidin et al.			
QU	AL	US2003/0112011A1	02-2003	Wada et al.			

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		Document Number	Date	Country	Class	Subclass	Translation	
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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EXAMINER: Jennifer M. Kennedy

DATE CONSIDERED: Feb 13, 2005

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WELLS ST. JOHN, P.S.

5098383424 P.03/03

Form PTO-144W		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. N122-2157		SERIAL NO. 10524716	
LIST OF ART CITED BY APPLICANT (If no answer check (if necessary))				APPLICANT Lan C. Tran			
				FILING DATE July 21, 2001		GROUP 2011	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Applicable
JL JL JL	AA	5,941,785	11-1998	Isbikawa			/
	AB	6,131,458 B1	12-2001	Anjum et al.			
	AC	6,211,744 B1	06-2001	Su et al.			
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FOREIGN PATENT DOCUMENTS							
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EXAMINER		DATE CONSIDERED					
		JENNIFER M. KENNEDY Feb 15 2005					
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1/1 IDS 11/1/04

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WELLS ST. JOHN, P.S.

5098383424 P.03/03

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M22-2357		SERIAL NO. 10624.716	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT LUAN C. TRAN			
				FILING DATE July 21, 2003		GROUP 2811	
U.S. PATENT DOCUMENTS							
Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate	
JM	AA	3,767,557	06-1998	Kilgus			
JM	AB	3,389,295	11-1994	Vinal			
JM	AC	3,397,919	03-1995	Moschi			
JM	AD	3,873,728	04-1999	Ishizu			
JM	AE	3,672,526	09-1997	Kawamura			
JM	AF	5,723,714	07-1993	Wakamiya et al.			
JM	AG	5,440,161	08-1995	Iwamatsu et al.			
JM	AH	5,335,012	10-1994	Yamaguchi et al.			
JM	AI	3,836,226	01-1999	Wu			
JM	AJ	5,877,036	13-1999	Wu			
JM	AK	6,318,113 B1	12-2103	Buykowski			
JM	AL	6,642,581 B2	11-2103	Matsuda et al.			
JM	AM	6,297,082 B1	10-2101	Lin et al.			
JM	AN	US2002/0043692A1	04-2002	Maeda et al.			
JM	AO	US2003/0189231	10-2103	Clevenger et al.			
FOREIGN PATENT DOCUMENTS							
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EXAMINER <u>Jennifer M. Kennedy</u> DATE CONSIDERED <u>Feb 15 2005</u> <small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 409; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							